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8/A 3/18/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:) }	
Hiromichi Ohta, et al.) Before the Examiner)	
Application Serial No:) Jason Vincent V. de la Peña	
09/615,883) Group Art Unit 1775	I hereby certify that this correspondence is being deposited with the United States
Filed July 14, 2000))	Postal Service as first class mail in an envelope addressed to the Assistant Commissioner for Patents, Washington,
TITLE: LOW-RESISTANCE ITO THIN FILM AND METHOD FOR MANUFACTURING SUCH A FILM)) February 13, 2002	D.C. 20231 on: February 13, 2002 (Date of Deposit)
WANDI ACTORING SOCITATIEM	,	Vincent O. Wagner Name of Registered Representative
		Signature
		February 13, 2002 Date of Signature

RESPONSE

Commissioner of Patents Washington, D.C.

In response to the Office Action dated August 14, 2001 please enter the following amendments and consider the accompanying remarks. Filed concurrent with this Response is Request for a three-month Extension of Time to respond this Office Action and an Information Disclosure Statement. Additionally, please charge any fees that may be due to Deposit Account No. 23-3030, but do not include any payment of issue fees that are or may become due.

03/05/2002 SFELEKEI 00060020 00615883

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